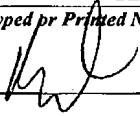


CERTIFICATE OF TRANSMISSION BY FACSIMILE (37 CFR 1.8)			Docket No. 12688A
Applicant(s): Hidemitsu Aoki, et al.			
Serial No. 10/075,566	Filing Date February 13, 2002	Examiner Saeed Chaudhry	Group Art Unit 1746
Invention: METHOD FOR CLEANING SEMICONDUCTOR WAFER AFTER CHEMICAL MECHANICAL POLISHING ON COPPER WIRING			
<p>I hereby certify that this <u>TRANSMITTAL (w/ Certified Copy of Japanese Patent Appln. No. 10-138365)</u> (Identify type of correspondence)</p> <p>is being facsimile transmitted to the United States Patent and Trademark Office (Fax. No. <u>(571) 273-1296</u>)</p> <p>on <u>February 5, 2004</u> (Date)</p> <p>Richard J. Danyko (Typed or Printed Name of Person Signing Certificate)</p> <p> (Signature)</p> <p>Note: Each paper must have its own certificate of mailing.</p>			

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Applicant(s):	Hidemitsu Aoki, et al.	Examiner:	Saeed Chaudhry
Serial No.:	10/075,566	Art Unit:	1746
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For:	METHOD FOR CLEANING SEMICONDUCTOR WAFER AFTER CHEMICAL MECHANICAL POLISHING ON COPPER WIRING	Dated:	February 5, 2004

Commissioner for Patents
Mail Stop Non-Fee Amendment
Arlington, VA 22313

TRANSMITTAL

Sir:

Pursuant to the undersigned's conversation with Examiner Chaudhry, enclosed is a facsimile of the certified copy of the priority document.

Respectfully submitted,



Richard J. Danyko
Registration No. 33,672

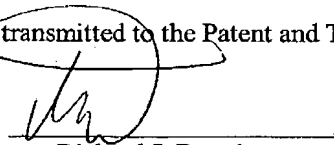
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